Titles of Most Frequently Occurring Classifications of Patents Returned
From A Search of 09698497 on October 25, 2001

3 438/692 (0 OR, 3 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/689 CHEMICAL ETCHING
438/690 .Combined with the removal of material by nonchemical means (e.g., ablating, abrading, etc.)
438/691 ..Combined mechanical and chemical material removal
438/692 ...Simultaneous (e.g., chemical-mechanical polishing, etc.)

2 318/609 (0 OR, 2 XR)
Class 318 : ELECTRICITY: MOTIVE POWER SYSTEMS
318/560 POSITIONAL SERVO SYSTEMS (E.G., SERVOMECHANISMS)
318/609 ."Reset" systems (P.I.)

2 330/252 (0 OR, 2 XR)
Class 330 : AMPLIFIERS
330/250 WITH SEMICONDUCTOR AMPLIFYING DEVICE (E.G., TRANSISTOR)
330/252 .Including differential amplifier

2 365/201 (0 OR, 2 XR)
Class 365 : STATIC INFORMATION STORAGE AND RETRIEVAL
365/189.01 READ/WRITE CIRCUIT
365/201 .Testing

2 438/424 (2 OR, 0 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/400 FORMATION OF ELECTRICALLY ISOLATED LATERAL SEMICONDUCTIVE STRUCTURE
438/424 .Grooved and refilled with deposited dielectric material

2 438/427 (0 OR, 2 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/400 FORMATION OF ELECTRICALLY ISOLATED LATERAL SEMICONDUCTIVE STRUCTURE

438/424 .Grooved and refilled with deposited dielectric material
438/427 ..Refilling multiple grooves of different widths or depths

2 438/435 (0 OR, 2 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/400 FORMATION OF ELECTRICALLY ISOLATED LATERAL SEMICONDUCTIVE STRUCTURE
438/424 .Grooved and refilled with deposited dielectric material
438/435 ..Multiple insulative layers in groove

2 438/443 (0 OR, 2 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/400 FORMATION OF ELECTRICALLY ISOLATED LATERAL SEMICONDUCTIVE STRUCTURE
438/439 .Recessed oxide by localized oxidation (i.e., LOCOS)
438/443 ..Etchback of recessed oxide

2 438/700 (0 OR, 2 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/689 CHEMICAL ETCHING
438/694 .Combined with coating step
438/700 ..Formation of groove or trench

2 438/701 (0 OR, 2 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/689 CHEMICAL ETCHING
438/694 .Combined with coating step
438/700 ..Formation of groove or trench
438/701 ...Tapered configuration

2 438/702 (0 OR, 2 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/689 CHEMICAL ETCHING
438/694 .Combined with coating step
438/700 ..Formation of groove or trench
438/702 ...Plural coating steps

2 438/792 (0 OR, 2 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/758 COATING OF SUBSTRATE CONTAINING SEMICONDUCTOR REGION OR OF SEMICONDUCTOR SUBSTRATE
438/778 .Insulative material deposited upon semiconductive substrate
438/791 ..Silicon nitride formation
438/792 ...Utilizing electromagnetic or wave energy (e.g., photo-induced deposition, plasma, etc.)

2 438/793 (0 OR, 2 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/758 COATING OF SUBSTRATE CONTAINING SEMICONDUCTOR REGION OR OF SEMICONDUCTOR SUBSTRATE
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438/792 ...Utilizing electromagnetic or wave energy (e.g., photo-induced deposition, plasma, etc.)
438/793 ....Organic reactant

2 438/794 (0 OR, 2 XR)
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438/758 COATING OF SUBSTRATE CONTAINING SEMICONDUCTOR REGION OR OF SEMICONDUCTOR SUBSTRATE
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438/791 ..Silicon nitride formation
438/794 ...Organic reactant

2 700/83 (2 OR, 0 XR)
Class 700 : DATA PROCESSING: GENERIC CONTROL SYSTEMS OR SPECIFIC APPLICATIONS
700/1 GENERIC CONTROL SYSTEM, APPARATUS OR PROCESS
700/83 .Having operator control interface (e.g., control/display console)

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438/701 ...Tapered configuration

2 438/702 (0 OR, 2 XR)
Class 438 : SEMICONDUCTOR DEVICE MANUFACTURING: PROCESS

438/689 CHEMICAL ETCHING
438/694 .Combined with coating step
438/700 ..Formation of groove or trench
438/702 ...Plural coating steps

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2 438/443
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2 438/701
2 438/702
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2 438/794

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PLUS Search Results for S/N 09698497, Searched October 25, 2001

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6175279
6084474
6208581
5019736
5222043
5640534
5914885
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6131044
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